



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masahiro FURUSAWA et al.

Group Art Unit: 1762

Application No.: 10/028,712

Examiner: W. Markham

Filed: December 28, 2001

Docket No.: 111604

For: A METHOD FOR FABRICATING A SILICON THIN-FILM

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the November 18, 2003 Office Action, please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**